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SMP
5/13/83*

PATENT

0171-0819P

IN THE U.S. PATENT AND TRADEMARK OFFICE

Applicant: SHINGAGAWA, Tsutomu et al. Conf.:

Appl. No.: New Group:

Filed: February 13, 2002 Examiner:

For: PHOTOMASK BLANK, PHOTOMASK AND METHOD OF
MANUFACTURE

PRELIMINARY AMENDMENT

Assistant Commissioner for Patents
Washington, DC 20231

February 13, 2002

Sir:

The following preliminary amendments and remarks are respectfully submitted in connection with the above-identified application.

IN THE SPECIFICATION:

Please replace page 10 with the new page 10 attached hereto.